



Competence in Silicon

The numerous configurations of „interstitial boron“ and their involvement in ARP of LGADs

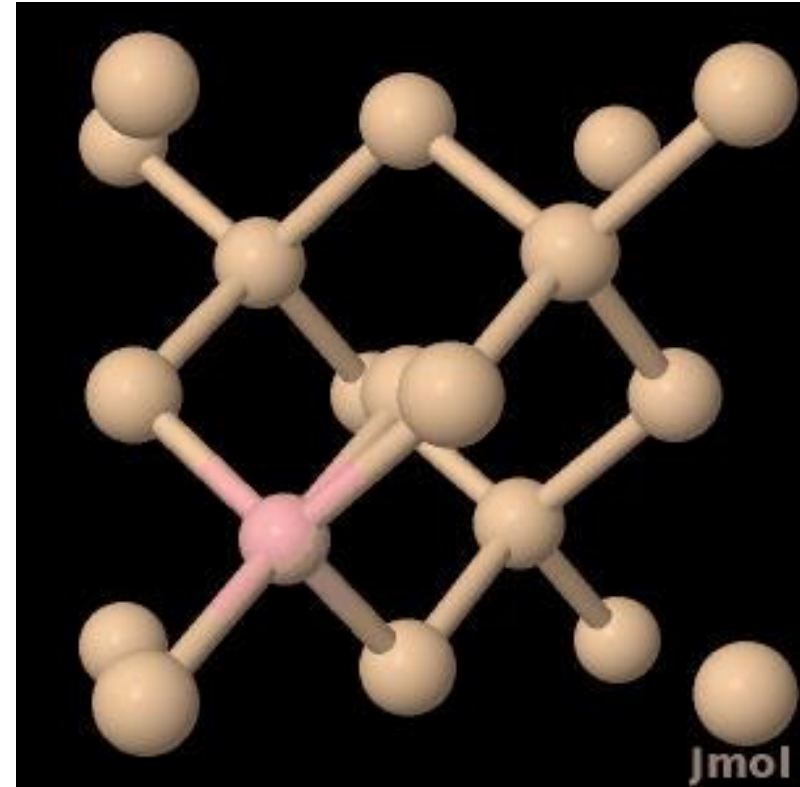
30.11.2023

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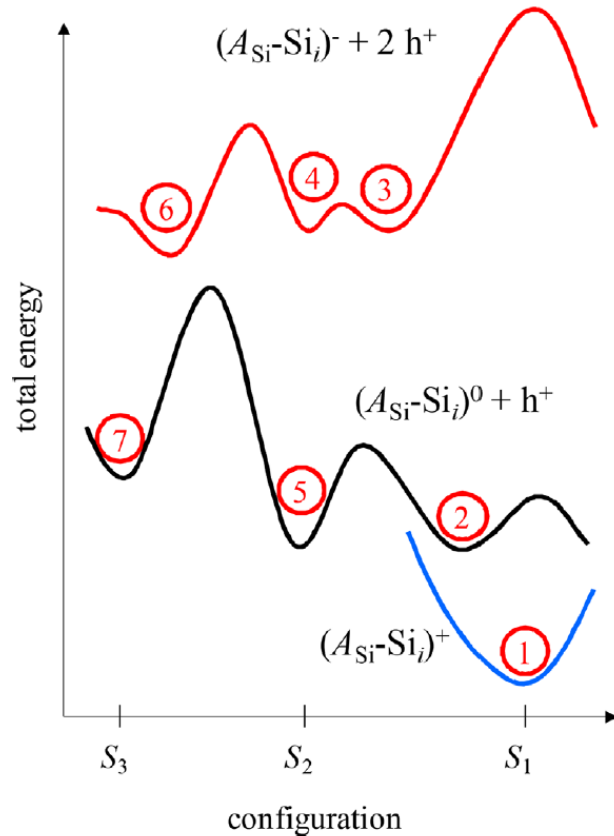
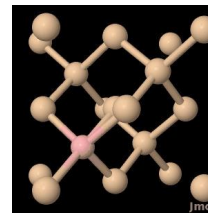
Existing A_{Si} - Si_i -defect model

A_{Si} - Si_i defect model

- A_{Si} : acceptor atom is close to its substitutional position
- Silicon interstitial is moving around (tetrahedral, hexagonal and split interstitial position assumed so far)
- Model and experimental evidence recently reviewed [1]

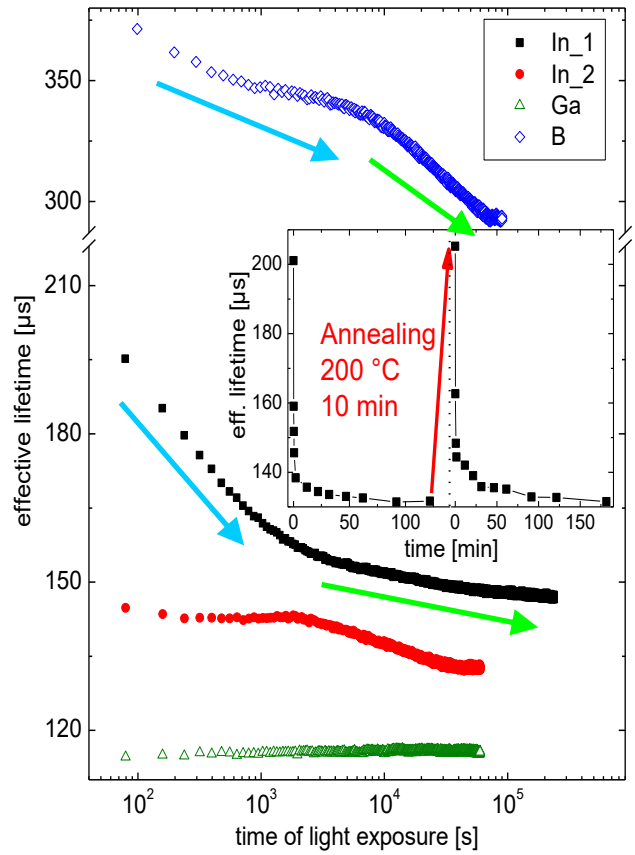
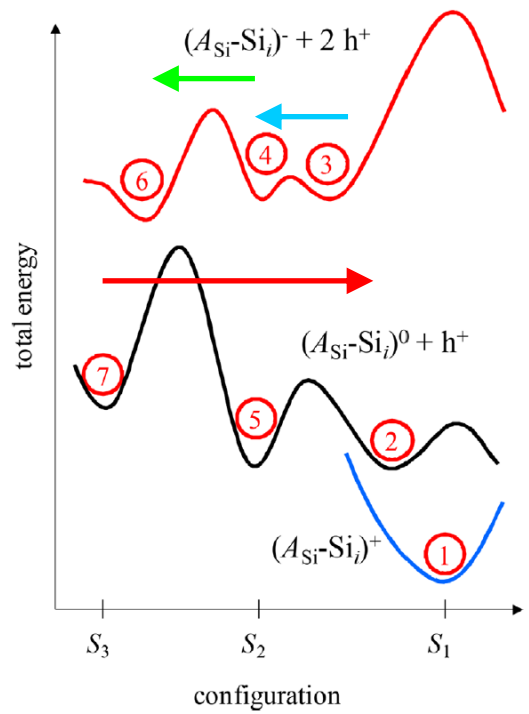


$A_{Si}-Si_i$ defect model



- Configuration coordinate total (electronic + elastic) energy diagram [1] deduced from simulation results of the silicon interstitial [2]
- Three charge states (+, 0, -) and three configurations (S_1 , S_2 and S_3) of $A_{Si}-Si_i$ exist within the model
- Energy barriers between configurations (e.g. E_{34} , E_{46})
- Negative charge state: S_3 energetically favored
- Neutral charge state: S_2 and S_1 energetically favored

Explanation of LID by $A_{Si}-Si_i$ defect model



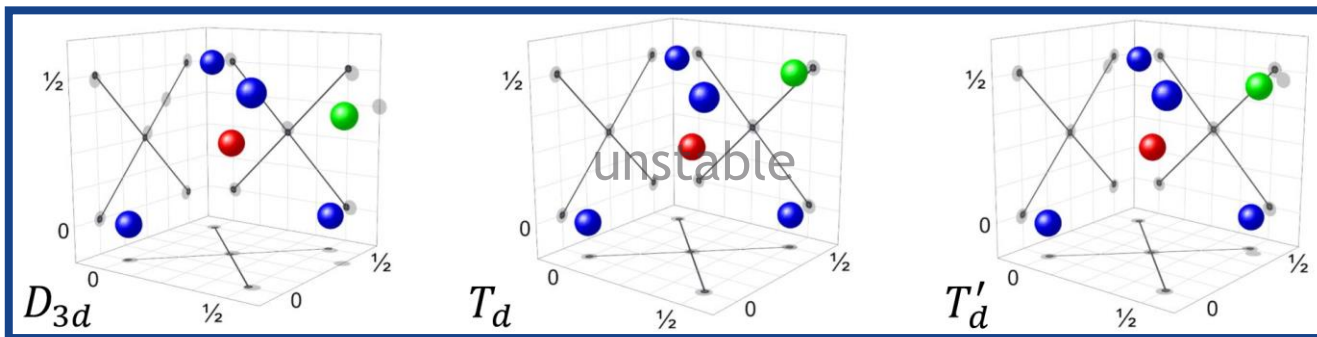
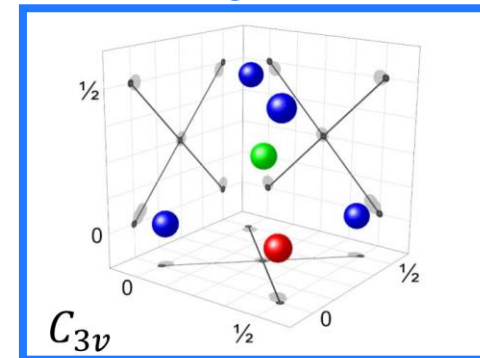
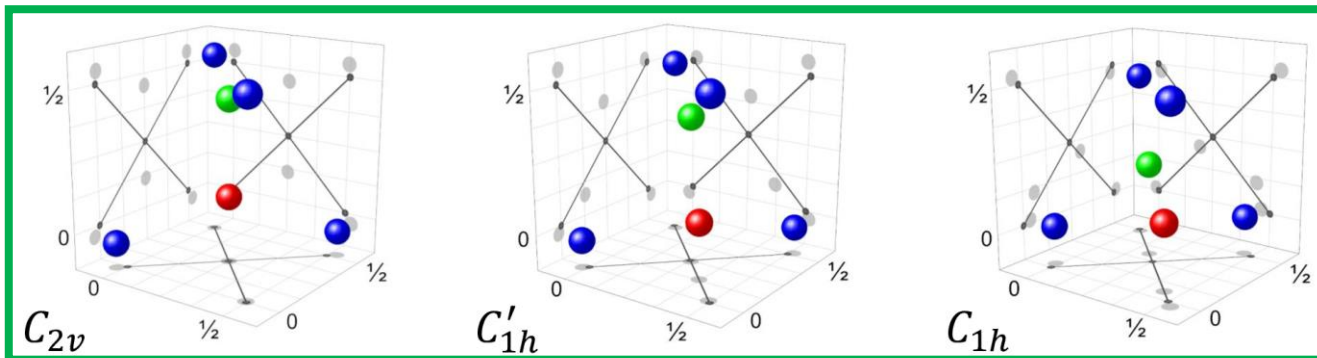
- **LID:** light-induced degradation in silicon solar cells [1]
- **Transition 1 to 3:** defect captures electrons under illumination
- **Transition 3 to 4:** thermally stimulated, fast component of LID (FRC)
- **Transition 4 to 6:** thermally stimulated, slow component of LID (SRC)
- **Transition 7 to 1:** thermally stimulated, recovery of defect, without illumination

Configurations of “interstitial boron” obtained by DFT calculations

DFT calculation of stable defect configurations

$B_i Si_i V$

$B_{Si} Si_i$



B_i

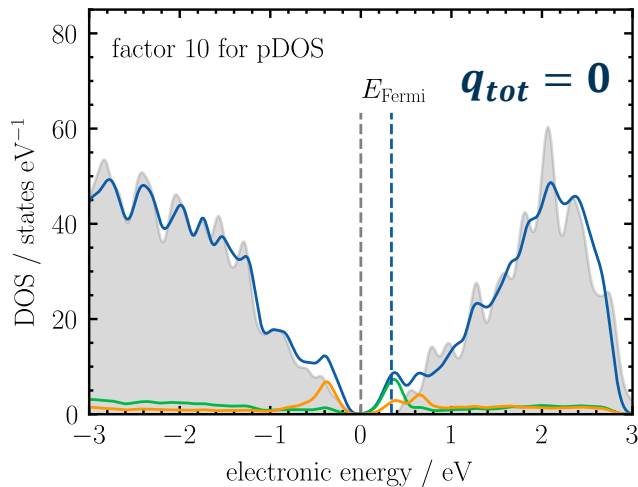
- Si Bulk
- Si defect
- B defect
- projection of atoms to $\{100\}$ planes
- projection of lattice sites to $\{100\}$ planes

● Six different stable configurations found

DFT calculation of density of states (DOS)

B_iSi_i defect (C_{1h})

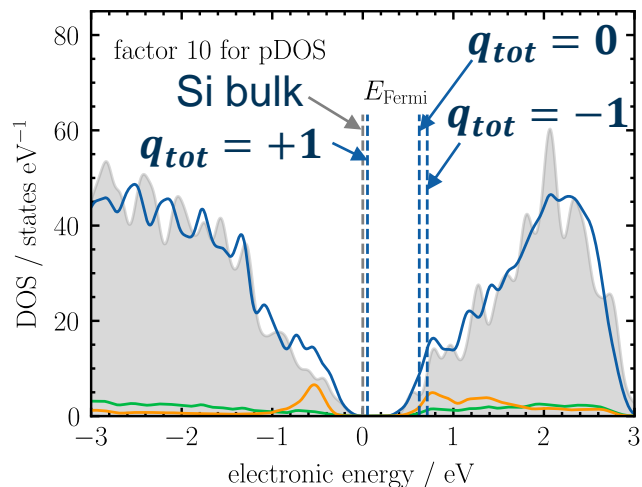
clean Si B_{Si} pDOS
total DOS Si_i pDOS



→ Deep donor

$B_{Si}Si_i$ defect (C_{3v})

clean Si B_{Si} pDOS
total DOS Si_i pDOS

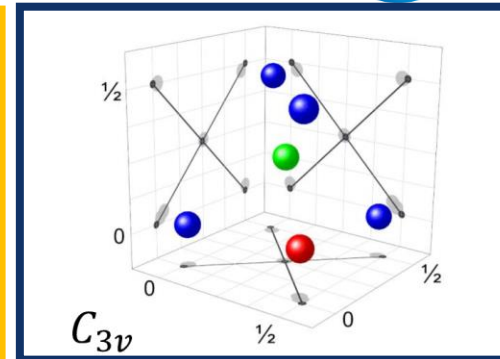
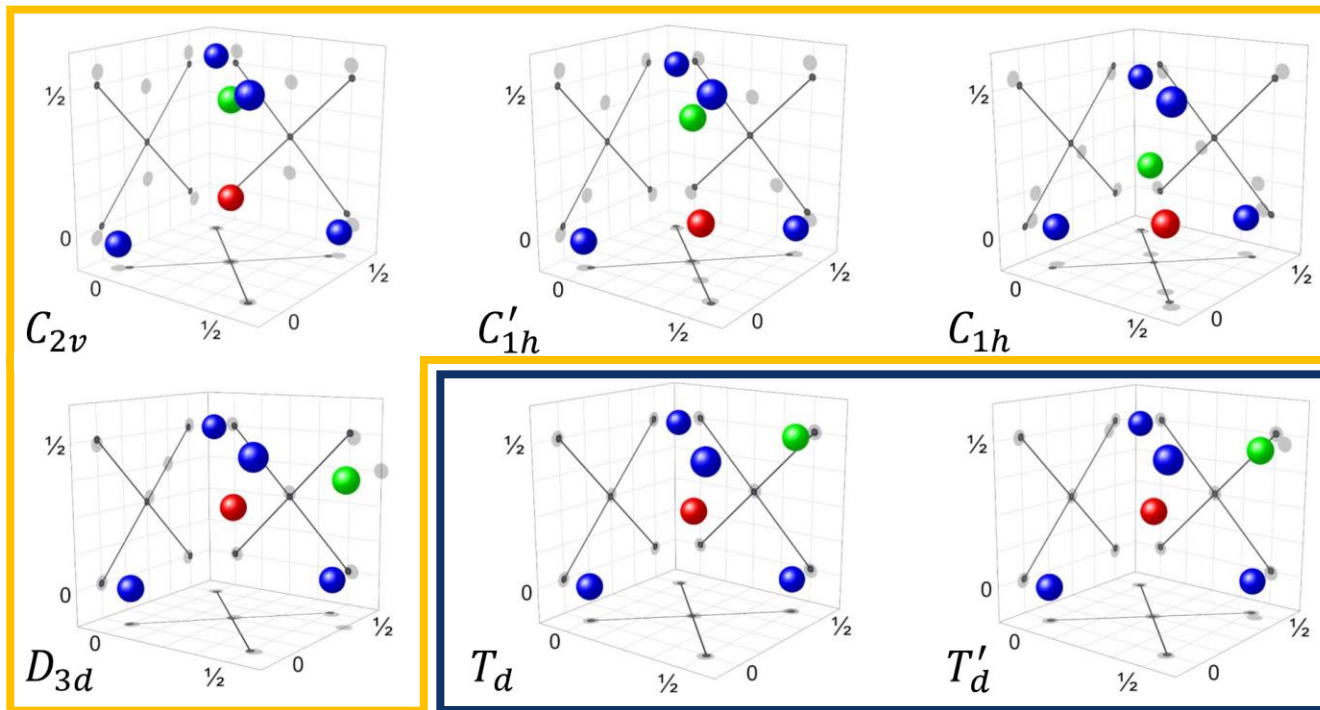


→ Shallow donor

- $B_{Si}Si_i$ defect in C_{3v} configuration is shallow donor

Calculated electronic defect states

deep



shallow

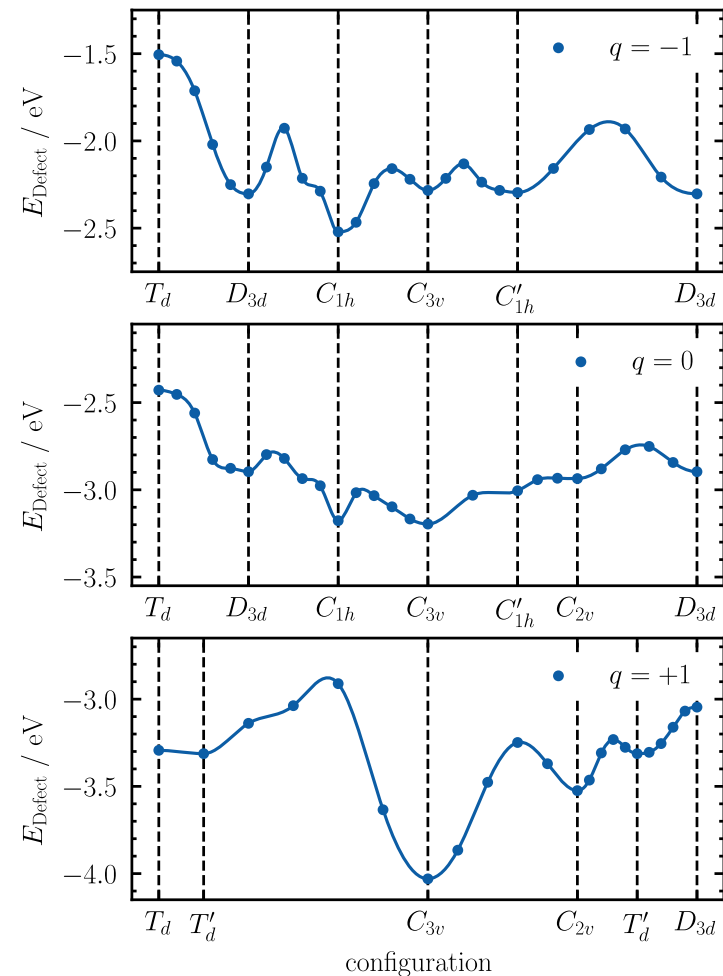
- Si Bulk
- Si defect
- B defect
- projection of atoms to {100} planes
- projection of lattice sites to {100} planes

● 4 deep and 3 shallow centers found

Defect energy landscape

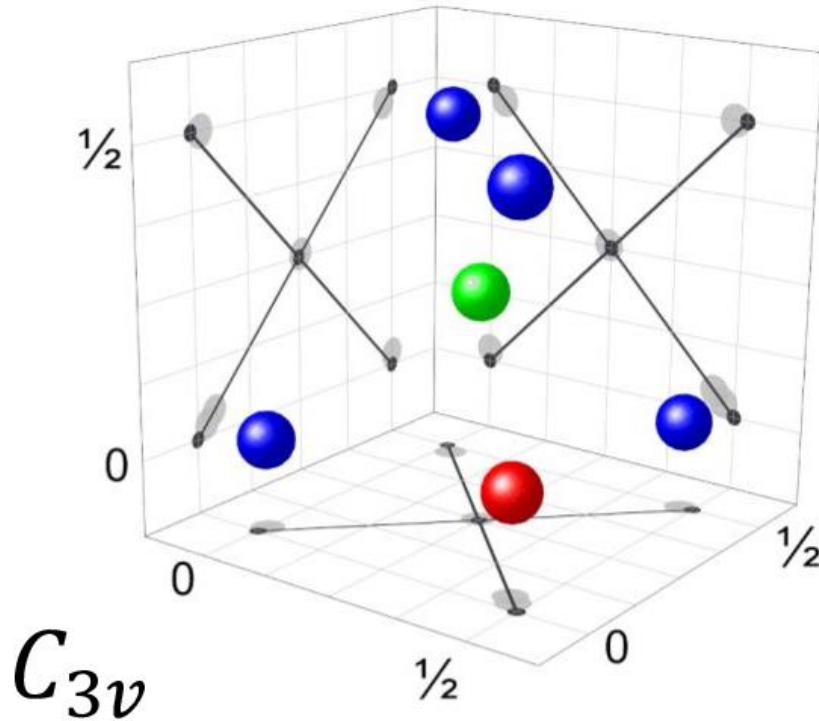
Calculated defect energy landscape

- Calculation of all Minimal Energy Paths (NEB method) between defect configurations for each charge state
- Ground state in positive charge state (p-type silicon) is C_{3v} configuration
- From DFT calculations: no energetical reason for the substitutional boron to follow the Watkins replacement reaction!



Explanation of ARP in LGADs by the B_{Si} - Si_i -defect mode

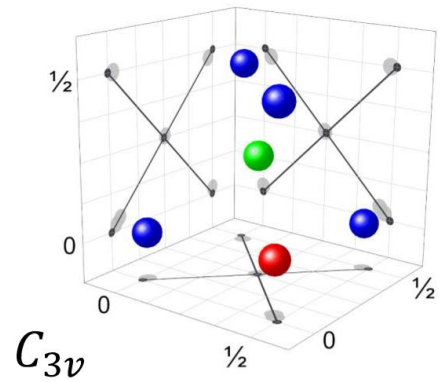
Explanation of ARP in LGADs by B_{Si_i} - Si_i -defect mode



- Irradiation removes silicon atoms from lattice positions
- At low temperatures ($\sim 20K$) the removed silicon atom moves due to the energy gained by the collision event and is eventually captured by substitutional boron. [1]
- At about room temperature the removed silicon atom might additionally diffuse thermally due to its weak mobility. [2]
- Shallow donor mode of the B_{Si_i} - Si_i -defect (C_{3v}) forms

Summary

- Comprehensive DFT calculations made for “interstitial boron”
- Six different stable configurations found
- Configuration with lowest energy in p-type silicon is C_{3v} with boron residing very close to regular lattice position
- C_{3v} configuration is found to be a shallow donor
- Explanation of acceptor removal phenomenon (ARP) in low-gain avalanche detectors (LGAD):
 - Substitutional boron acceptor captures silicon atom, which was removed from a lattice position by irradiation.
 - The resulting defect is a shallow donor.
 - Amplification property of the boron gain layer in LGADs gets lost by irradiation.



Thank you for your kind attention!

DFG Project SimASiSii:

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Thanks to RD50 for possibility to present crazy ideas!



Back-up

Possibility for silicon recoils to reach B atoms

- 1 MeV electron irradiation of silicon generates silicon recoils exhibiting kinetic energy
- ~10% of these recoils have more than 80eV
- ~50% of these 10% travel more than 1nm (SRIM)
- For 10^{16}cm^{-3} boron density every 23th of these left recoils is able to reach a boron atom
- If 10% of the silicon recoils reaching boron to form the $\text{B}_{\text{Si}}\text{-Si}_i$ -defect, a $\text{B}_{\text{Si}}\text{-Si}_i$ -defect density of about 10^{15}cm^{-3} is under typical conditions (electron current and duration) possible.
- => Sufficient to explain EPR signals [1] without assumption of fast defect diffusion [2]

